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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application Serial No. 10/671,922
Confirmation No. 8459
Filing Date September 24, 2003
Inventor..... Garo J. Derderian et al.
Assignee..... Micron Technology, Inc.
Group Art Unit..... 2812
Examiner Lynne Ann Gurley
Attorney's Docket No. MI22-2296
Customer No. 021567
Title: Atomic Layer Deposition Methods, and Methods of Forming Materials Over
Semiconductor Substrates

RESPONSE TO OCTOBER 18, 2005 FINAL OFFICE ACTION

Response to Accompany an RCE filing

To: Mail Stop RCE
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

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AMENDMENTS